

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Mieher, et al.

Attorney Docket No.:
KLA1P117X1D/1151/2

Application No.: 10/785,396

Examiner: Gordon J. Stock Jr.

Filed: February 23, 2004

Group: 2877

Title: APPARATUS AND METHODS FOR
DETECTING OVERLAY ERRORS USING
SCATTEROMETRY

Confirmation No. 6516

AMENDMENT A

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

It is respectfully submitted that the Examiner enters the following amendments in response to the Office Action dated 20 October 2006, a response to which is due 20 January 2007.

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims that begin on page 5 of this paper.

Remarks/Arguments begin on page 13 of this paper.